

**EE 130, Fall 1995  
Final  
Professor C. Hu**

Electric charge =  $q = 1.602 \times 10^{-19}$  C

Permittivity of vacuum = **epsilon not** =  $8.854 \times 10^{-14}$  F/cm

Free electron mass = **mo** =  $9.11 \times 10^{-31}$  kg

Boltzman's constant =  $k = 1.38 \times 10^{-23}$  J/degree K  
=  $8.62 \times 10^{-5}$  eV/degree K

Thermal voltage =  $V_t = kt/q = .026$  V at 300 K

Conversion Factors

1  $\text{\AA}$  =  $1 \times 10^{-8}$  cm

1 micrometer =  $1 \times 10^{-6}$  m =  $1 \times 10^{-4}$  cm

1 eV =  $1.6 \times 10^{-19}$  J

1 J =  $1 \times 10^7$  erg

Properties of Si at 300 K

Effective density of states for conduction band = **Nc** =  $2.8 \times 10^{19}$  cm<sup>-3</sup>

Effective density of states for valence band = **Nv** =  $1.04 \times 10^{19}$  cm<sup>-3</sup>

Intrinsic carrier concentration = **ni** =  $1.45 \times 10^{10}$  cm<sup>-3</sup>

Relative permittivity = **epsilon r** = 11.7

Relative permittivity of oxide = **epsilon ox** = 3.9

### **Problem #1a**

A uniformly doped Si sample has 10  $\mu$ m length and 10  $\mu$ m squared cross sectional area. 1V is applied across this sample. Suppose  $p = 1 \times 10^{14}$  per cm cubed and  $\mu_p = 500$  cm squared/V s. These values are valid for all of #1 Derive the expression  $\mu_p$  in terms of  $\tau_p$  and  $m_p$ .

### **Problem #1b**

Give two mechanisms of carrier scattering and state whether the rate of scattering for each mechanism increases or decreases as temperature increases.

### **Problem #1c**

Find the drift velocity of the carriers.

### **Problem #1d**

Find the current flowing through this sample.

### **Problem #1e**

What is the approximate hole velocity when 100V is applied

### **Problem #2a**

A simple circuit that functions as a temperature sensor forces a fixed forward-bias current **If** through a pn diode and monitors the resultant diode voltage, **Vf**. Derive an expression for **Vf** as a function of temperature T. The function may contain any semiconductor parameters usually considered known or given, e.g. **Eg**, **Na**, **tau n**, **Nc**, **Nv**, etc. Ignore the T dependence of all these parameters.

**Problem #2b**

For extra credit, give the answer to (a) in terms of  $E_g$ ,  $q$ ,  $kT$ ,  $I_f$ , and  $V_f$

**Problem #3a**

Consider a Schottky diode with this doping profile Sketch the  $1/C$  squared versus  $V$  (reverse bias voltage) curve. No need to find numerical values for  $C$ .

**Problem #3b**

Sketch the electric field profile for the bias condition when  $x_{dep} = 2 \text{ um}$ . No need to find numerical values of  $\epsilon$

**Problem #3c**

What is the applied bias in part (b)

**Problem #3d**

Derive an expression of  $C$  as a function of  $V$  for the case of  $x_d > 1 \text{ um}$

**Problem #3e**

Under forward bias, what is the main difference between the I-V characteristic of the Schottky diode and a pn-junction diode? Use 2 sentences or less.

**Problem #3f**

If you want an ohmic contact instead of a Schottky diode would you change the doping profile?

**Problem #4a**

Sketch the cross-section of a CMOS inverter in an n-well process. Label the nodes connected to power(VDD) and ground.

**Problem #4b**

Describe what latch-up is (now how it happens) and why it is a problem in 2 sentences

**Problem #4c**

Identify the parasitic NPN and PNP transistors in the sketch by connecting the BJT nodes to the corresponding MOSFET node with lines. (Note that not all MOSFET node may be involved.

NPN emitter NMOS source

NPN base NMOS drain

NPN collector n-well

PNP emitter PMOS source

PNP base PMOS drain

PNP collector p-substrate

### Problem #4d

In principle latch-up problems can be reduced by depressing the current gains of the BJT's. Indicate by arrows (latch-up reduced, enhanced, or unaffected) the effect of each of the following changes. Explain with very short phrases, e.g. base recombination time increases.

Increase n-well depth:

Increase n-well doping:

Increase p+ junction doping:

n+/p+ separation (distance) increase:

Add gold into Si substrate:

Increase gate oxide thickness:

### Problem #4e

It has been observed that the latch-up structure can tolerate a large trigger pulse without latching-up if the pulse is very short. Give a one or two sentence simple explanation for why latch-up has a time dependence.

### Problem #5a

Qualitatively sketch the C-V,  $I_d$ - $V_g$ , and  $I_d$ - $V_d$  curves for a NMOSFET in the following conditions. (where the dot line represents the curves before changing each parameter) Add positive charge in oxide:

### Problem #5b

$N_d$  decreases:

### Problem #5c

$\epsilon_{ox}$  increases:

### Problem #6a

Consider a NMOSFET with  $\epsilon_{ox} = 100 \text{ A}$ ,  $N_a = 5 \times 10^{16} \text{ cm}^{-3}$ , Assume  $L = 0.5 \mu\text{m}$ ,  $W = 10 \mu\text{m}$ ,  $\mu_n = 500 \text{ cm}^2/\text{V s}$ ,  $V_g - V_t = 3 \text{ V}$ , and  $\epsilon_{crit}$  (critical field for velocity saturation) =  $2 \times 10^4 \text{ V/cm}$  Without considering velocity saturation, what is  $I_d$  at  $V_d = 1 \text{ V}$

### Problem #6b

What is  $I_d$  at  $V_d = 1 \text{ V}$  with velocity saturation?

### Problem #6c

Calculate the subthreshold swing, S

### Problem #6d

As a result of the hot-electron effect,  $1 \times 10^{-7} \text{ cm}^{-2}$  of electrons are trapped at the oxide/Si interface. How much will  $V_t$  change? Will  $V_t$  increase (become more positive) or decrease?

**Problem #6e**

If  $V_t$  decreased by 0.1V as a result of hot-electron effect, by what ratio (factor) will  $I_d$  at  $V_g=0$  change? Will  $I_d$  increase or decrease?

**Problem #6f**

What phenomenon does the following figure illustrate?

**Problem #6g**

In (f), which company's technology is superior? Why is it considered superior?

**Problem #6h**

In (g), list two possible ways for this company to achieve this competitive advantage.

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